

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE



In re Patent Application of

Helen H. ZHU et al.

Application No.: 09/820,694

Filed: March 30, 2001

For: METHOD OF PLASMA ETCHING
SILICON NITRIDE

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) Group Art Unit: 2823
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) Examiner: J. J. Maldonado
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) Confirmation No.: 7374
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REQUEST FOR INTERVIEW

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

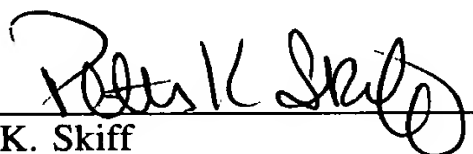
Sir:

The undersigned requests an interview with the Examiner before issuance of a first action final rejection. Please contact the undersigned at the (703) 838-6560.

Respectfully submitted,

BURNS, DOANE, SWECKER & MATHIS, L.L.P.

Date March 19, 2004
P.O. Box 1404
Alexandria, VA 22313-1404
(703) 836-6620

By: 
Peter K. Skiff
Registration No. 31,917

VA 83939.1